

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Trung T. Doan

Serial No.: 09/133,989

Filed: August 14 1998

For: CHEMICAL DISPENSING SYSTEM FOR
SEMICONDUCTOR WAFER PROCESSING

§
§ Group Art Unit: 1734
§
§ Examiner: L. Edwards
§
§ Atty. Docket: 93-0421.03
§
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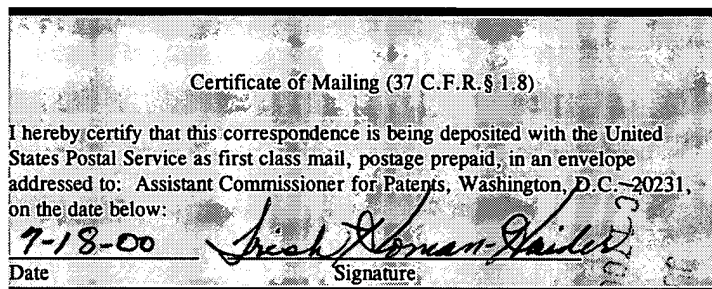
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#7/B

FIRST AMENDMENT AND ELECTION

IN RESPONSE TO THE OFFICE ACTION OF MARCH 21, 2000

Assistant Commissioner for Patents
Washington, D.C. 20231



Dear Sir:

Per the Examiner's Office Action of March 21, 2000, please amend the above application as follows.

IN THE SPECIFICATION

Please delete the following text that Applicant added after the title as indicated in the Preliminary Amendment:

"RELATED APPLICATIONS

This application is a continuation of U.S. Application Serial Number 08/944,135, which is a file wrapper continuation of U.S. Application Serial Number 08/618,072, filed February 27, 1996."

(N.E.)

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